

Lecture “Nanotechnology”

Artur Erbe / Jürgen Fassbender

Contents:

Introduction:

1. Why Nanotechnology?
 - a. Basic physics
 - b. Quantum effects
 - c. Applications
2. Applications and materials
 - a. Semiconductors
 - b. Magnetism
 - c. Plasmonics
 - d. Metamaterials

Fabrication methods:

3. Top-down approach
 - a. General approaches
 - b. Positive/negative techniques; lift-off; wet and dry etching
4. Top-down-approach
 - a. Optical lithography
 - b. Electron beam lithography
 - c. Focused ion beam
 - d. Nanoimprint
5. Bottom-up approach
 - a. Nanoparticles
 - b. Fullerenes
 - c. Graphene

6. Bottom-up approach
 - a. Basic principles of self-organization
 - b. Nanosphere lithography
 - c. Micelles
 - d. Ion erosion
 - e. Alumina templates

Characterization techniques:

7. Forces at the nanoscale
 - a. Comparison macroscale - nanoscale
 - b. Van der Waals interaction
 - c. Casimir force
 - d. Dipolar forces (magnetic stray fields)
8. Scanning probe microscopy (SPM)
 - a. Scanning tunneling microscope (STM)
 - b. Atomic force microscope (AFM) and related techniques (MFM, SCM)
 - c. Manipulation of surfaces using SPM
 - d. Scanning nearfield microscopy (SNOM)
9. Local characterization of topography and elementary composition
 - a. Scanning electron microscopy
 - b. Transmission electron microscopy, incl. EDX and EELS
 - c. Secondary ion mass spectroscopy
10. Local characterization of magnetic properties
 - a. Kerr microscopy
 - b. Lorentz- microscopy
 - c. X-ray magnetic circular dichroism (XMCD)
 - d. Photo-emission electron microscopy (PEEM)
 - e. Transmission x-ray microscopy (TXM)
 - f. Holography

Special applications:

11. Molecular machines

12. Lab-on-a-chip

13. Photonic crystals

14. Magneto resistance and spin transfer torque

15. Plasmonics, metamaterials